

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

YAMAMUKA et al.

Application No.: Unassigned

Art Unit: Unassigned

Filed: July 6, 2001

Examiner: Unassigned

For: VAPORIZING DEVICE
FOR CVD SOURCE
MATERIALS AND CVD
APPARATUS
EMPLOYING THE SAME

PRELIMINARY AMENDMENT

Commissioner for Patents
Washington, D. C. 20231

Dear Sir:

Prior to the examination of the above-identified patent application, please enter the following amendments and consider the following remarks.

IN THE CLAIMS

Cancel claims 1-13 and substitute the indicated claims therefor:

14. (New) A vaporizing device for vaporizing chemical vapor deposition (CVD) source materials comprising:

a vaporizer for vaporizing introduced CVD source materials by heating, the vaporizer including a chamber for vaporization of the CVD source materials, the chamber having an inlet for introducing the CVD source materials into the chamber and a heat conductive chamber wall heated during vaporization of the CVD source materials,